WHAT IS CLAIMS IS:

1. An inspection device, comprising a storage means for storing the images obtained and a display means equipped with the first display area for displaying multiple images stored in the storage means and the second display area for displaying the images which are classified according to the characteristics of the displayed images (called the classified images); wherein the display means displays the class of the specimen, displays the sub class which is set manually for each class, and also displays the images selected by the sub class as a mass of the classified images for each sub class.

2. An inspection device according to Claim 1, wherein the classified images are grouped and displayed for each common sub class.

3. An inspection device according to Claim 1, wherein the classified images are compared with the confirmation image of the instruction and the result are displayed as a list, and also the sub class of the classified images are changed and the result be displayed again.

4. An inspection device according to Claim 1, which is equipped with the third display area for displaying the right, left and front enlarged images of the specimen of an image selected from the displayed images.

5. An inspection device according to Claim 1, wherein the obtained images are displayed as a mass of points in time series and, at the same time, correlation with the

multiple images displayed in the first display area is displayed in the mass for recognition.

6. An inspection method which obtains images of a specimen and stores the images, displays the multiple stored images in the first display area, and displays the classified images which are classified according to the characteristics of the displayed images in the second display area; wherein the class of the specimen is displayed automatically, sub class is set manually for each class and displayed, and the images selected by the sub class are displayed as a mass of the classified images for each sub class.

7. An inspection method according to Claim 6, wherein an image is selected from the displayed images and the right, left and front enlarged images of the specimen are displayed for the selected image.

8. An inspection method according to Claim 6, wherein the specimen represents a semiconductor wafer, the class represents the defect classification of the semiconductor wafer and 2 to 5 common characteristics specific to the semiconductor wafer are set as the class.

9. An inspection method according to Claim 6, wherein the result of the classification by the class is statistically processed for each sub class.

10. An inspection method which obtains images of a specimen and stores the images, displays the multiple stored images in the first display area, and displays the classified images which are classified according to the

characteristics of the displayed images in the second display area; wherein the class of the specimen is displayed automatically, the images are displayed in the number of more than 6x6 but less than 9 x 9 in the first display area, sub class is set manually for each class and displayed, and the images selected by the sub class are displayed in the number of 4 to 6 as the classified images for each sub class.